

Title (en)
DEFORMATION MEASURING DEVICE

Title (de)
VERFORMUNGSMESSER

Title (fr)
DISPOSITIF DE MESURE DE DEFORMATION

Publication
EP 1127243 B1 20061102 (DE)

Application
EP 99963212 A 19991104

Priority
• DE 9903543 W 19991104
• DE 19850872 A 19981104

Abstract (en)
[origin: WO0026608A2] The invention relates to a micromechanical sensor comprising electrodes (1, 2) which are arranged on a substrate, and comprising electrode bars (A) made of silicon that can move with regard to the electrodes. A deformation of the substrate is measured by determining the differential changes in capacity of these electrode bars in comparison to the adjacently arranged electrodes. Two groups of electrode bars are preferably used which are interlocked with one another in an alternating comb-like manner, which, separate from one another, are interconnected at the ends thereof in an electrically conductive manner, and which are anchored on the substrate.

IPC 8 full level
G01B 7/16 (2006.01); **G01L 5/00** (2006.01); **G01N 27/22** (2006.01)

CPC (source: EP US)
G01B 7/22 (2013.01 - EP US)

Designated contracting state (EPC)
DE FR GB IT

DOCDB simple family (publication)
WO 0026608 A2 20000511; **WO 0026608 A3 20000727**; DE 59913964 D1 20061214; EP 1127243 A2 20010829; EP 1127243 B1 20061102; JP 2002529684 A 20020910; US 2001048139 A1 20011206

DOCDB simple family (application)
DE 9903543 W 19991104; DE 59913964 T 19991104; EP 99963212 A 19991104; JP 2000579944 A 19991104; US 84991101 A 20010504